

TECHNICAL SPEC FOR Wet processing system

System Model: 10432

LAM Ontrak Synergy

Wafer size: 6inch

Process: cleaning, after tungsten & process after CMP

Chemicals used: DIwater & NH4OH

Wafer material: Si

SMIF: NO

Input station: installed & water spray available

Brush module: part number 12-8800-167

Hastelloy carriage: installed

Process bowl: Sink, spin station 13inch

Heat lamp yes

Edge gripping unload handler: YEs

Dual sensor blade loader: yes

Output station: part number 12-8872-196

Pumps: NA

Controllers: Gespac

SECS: secs communication installed

Vintage:

Missing parts: none

Defected parts: none

Software: 2.3.8

Operating system: OS-9

Photos to Collect

- All 4 sides
- Process module
- Control panel
- Robot
- Chemical cannisters
- Gauges/Valves
- Pumps
- Inside all cabinets (boards, electronics and chemicals)
- Serial plate
- Spare parts, manuals (if any)